

FEMTOprint



GAGNANT
Grand Prix des Exposants

FEMTOPRINT® – Mechanics, fluidics, optics meet in a monolithic 3D micro device out of glass

04.06.2015 – Andrea LOVERA

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Via Industria 3 – CH 6933 Muzzano



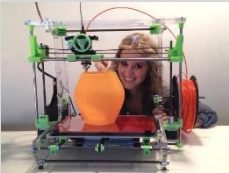
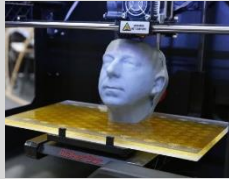
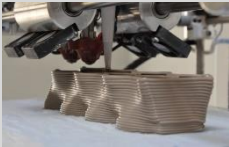
SWISS PHOTONICS

INDEX

- 3D PRINTING
- FEMTOPRINT® TECHNOLOGY
- APPLICATIONS
- POLISHING
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3D PRINTING

Have heard about 3D printing?



additive
manufacturing

FEMTOprint



subtracting
manufacturing

3D PRINTING

Have heard about 3D printing?



Pillar ϕ 5mm



Pillar ϕ 20 μ m

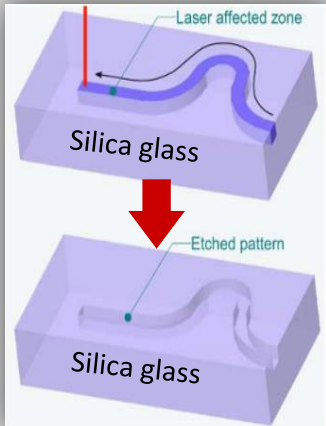
FEMTOprint

subtracting
manufacturing

The complex block is enclosed in a red border. At the top, the text 'FEMTOprint' is displayed in a red and grey font. Below this is a collage of three images: a glowing, fiber-like structure with a central junction; a close-up of a micro-machined metal part with a complex, curved shape; and a close-up of a human fingerprint with a tiny white mark on the ridge. At the bottom of the block, the text 'subtracting manufacturing' is written in a grey font.

FEMTOPRINT® TECHNOLOGY

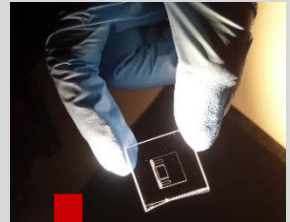
Selective subtracting manufacturing



Laser exposure



Chemical etching

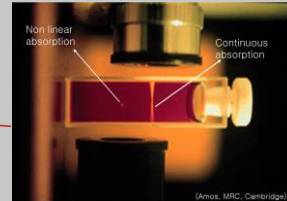
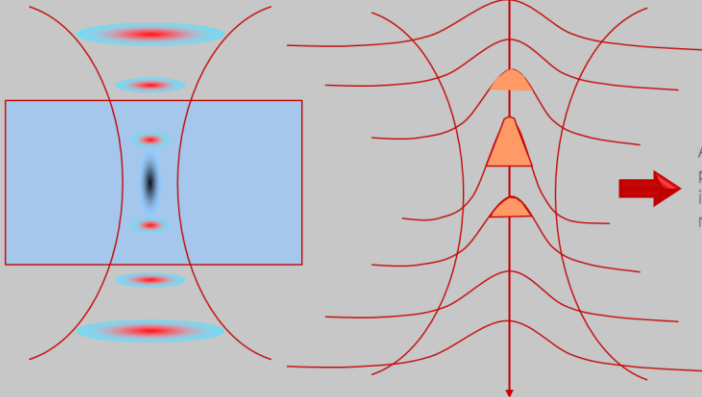


FEMTOPRINT® TECHNOLOGY

How it works

For transparent material, the energy can be absorbed in the bulk!

► Non linear absorption



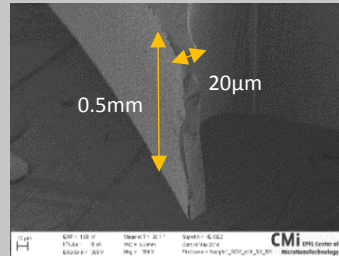
Absorption only takes place if a focused intensity threshold is reached

FEMTOPRINT® TECHNOLOGY

Process parameters

Resolution and tolerances

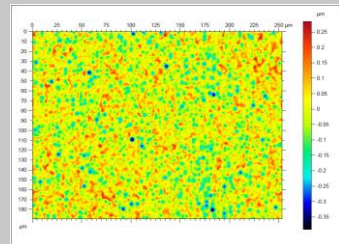
- Process resolution $1\mu\text{m}$
- Tolerances for 3D parts $\pm 2\mu\text{m}$
- Aspect ratio $\gg 1:50$
- Repeatability $1\mu\text{m}$



Surface quality

- After etching $R_a < 80\text{nm}$
- No laser writing pattern visible
- Polishing available for $R_a < 10\text{nm}$

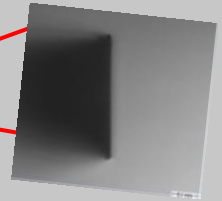
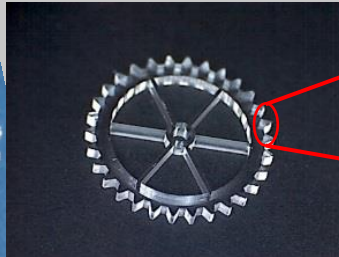
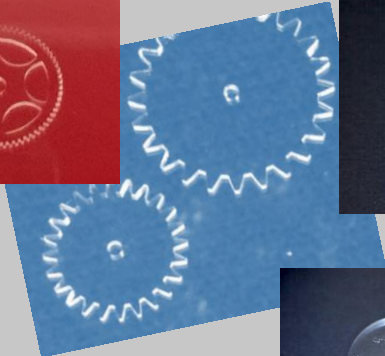
ISO 25178			
Height Parameters			
Sq	0.08174	μm	Root mean square height
Sp	0.2843	μm	Maximum peak height
Sv	0.3898	μm	Maximum pit height
Sz	0.6741	μm	Maximum height
Sa	0.06446	μm	Arithmetic mean height



APPLICATIONS

2.5D Micromechanics Devices

Transparent movements for watches



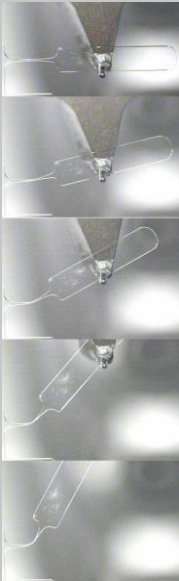
Very smooth
sidewalls!



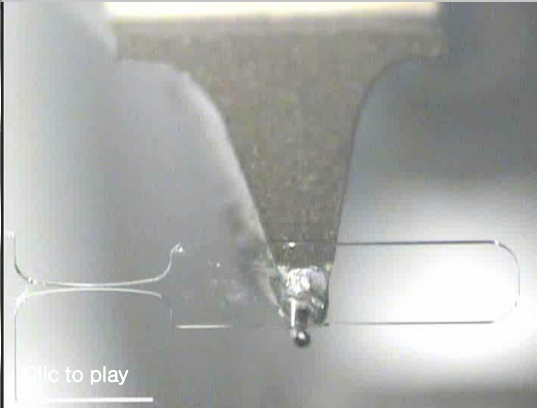
Thickness: 0.5mm
Material: fused silica

APPLICATIONS

Micromechanics



Fused silica flexure



Optical Materials Express, 1, 816–831 (2011)

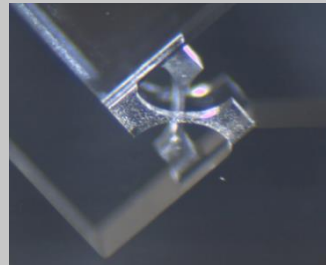
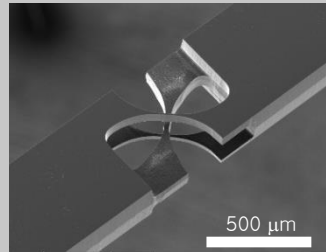
APPLICATIONS

Micromechanics

3D Mechanical devices Hinges



Galatea Project (TU/e) (2013)

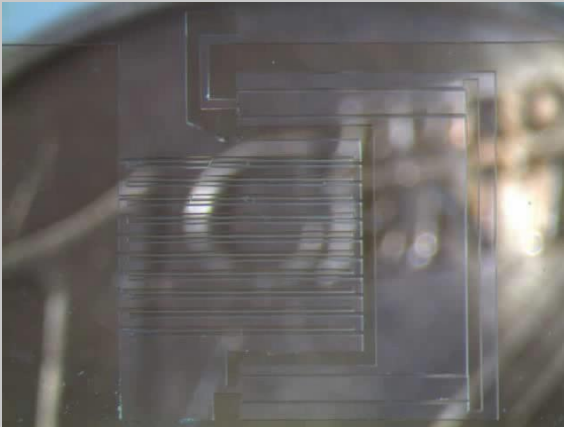


APPLICATIONS

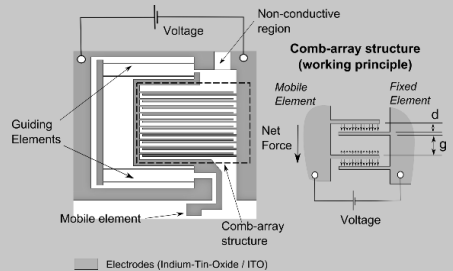
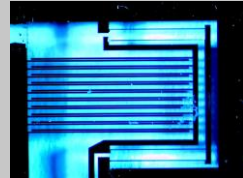
Micromechanics

MEMS

Sensors, Actuators



Thickness: 0.5mm
Material: fused silica

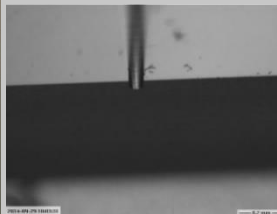
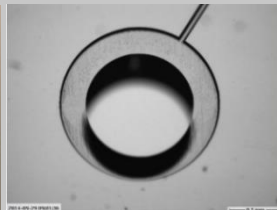


APPLICATIONS

Microfluidics – Biomed

3D Microfluidic device for cells analysis

Multilevel microfluidic chip with integrated access holes



L. Campo-Deaño, S. Martínez-Aranda and F.J. Galindo-Rosales

Financial support from FCT, COMPETE and FEDER through project EXPL/EMS-TRA/2306/2013 and grants IF/00148/2013 and IF/00190/2013.

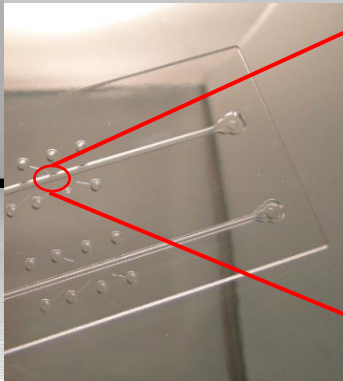
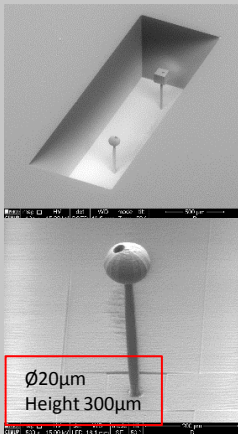
APPLICATIONS

Microfluidics – Biomed



3D Microfluidic Device

3D Targets inside microfluidic devices



L. Campo-Deaño, S. Martínez-Aranda and F.J. Galindo-Rosales
Financial support from FCT, COMPETE and FEDER through project EXPL/EMS-TRA/2306/2013 and grants IF/00148/2013 and IF/00190/2013.

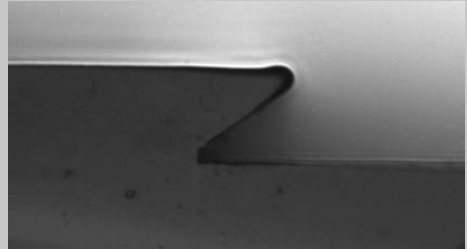
APPLICATIONS

Microfluidics – Biomed

3D Microfluidic Device

The sidewalls can be fully controlled

- Straight sidewalls channel
- Tilted sidewalls channel

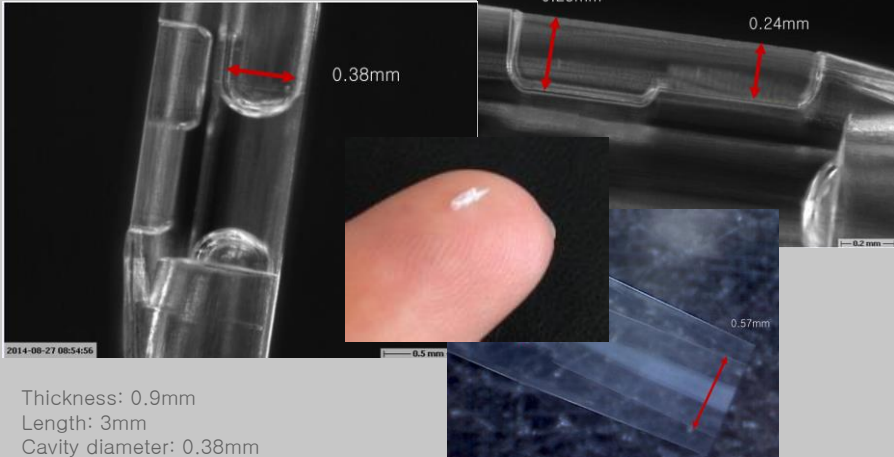


APPLICATIONS

Microfluidics – Biomed

3D Catheter tip

With housing for monitoring tool



Thickness: 0.9mm

Length: 3mm

Cavity diameter: 0.38mm

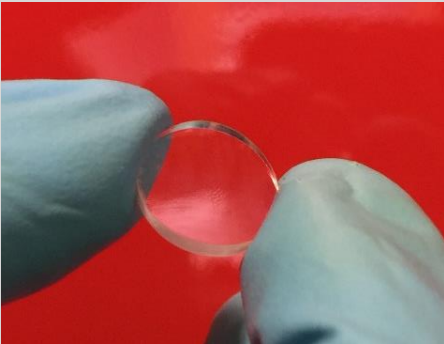
Material: fused silica

APPLICATIONS

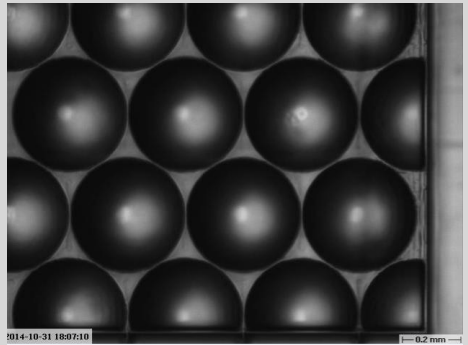
Optics – Lenses

Macro lens

For optical microscopes

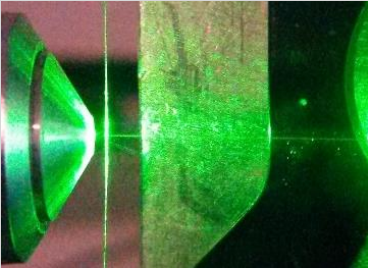


Microlenses



APPLICATIONS

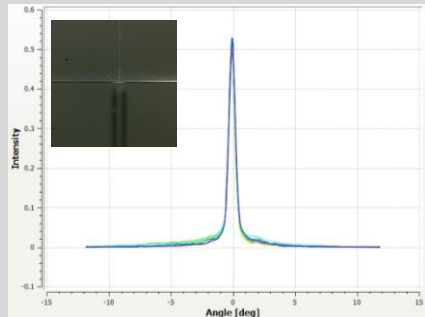
Optics – Waveguides



- Fabrication of optical devices
- Integration within existing microfluidic or mechanical devices for sensing

Performances

- Resolution $2\mu\text{m}$ (XY), $8\mu\text{m}$ (Z)
- Refractive index increase > 0.01
- Losses $< 0.1\text{dB/cm}$

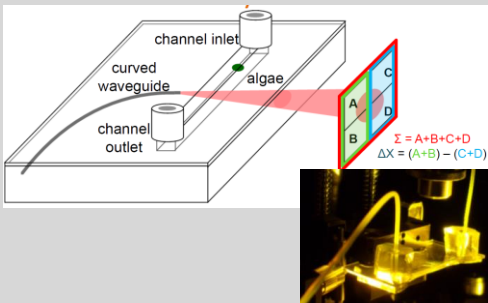


APPLICATIONS

Optics – Waveguides

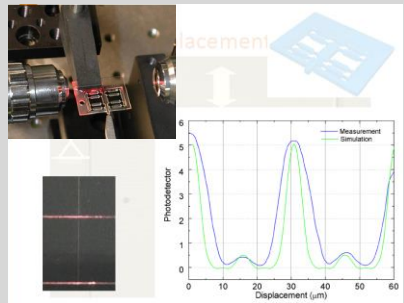
- Examples of devices exploiting waveguide detection

Microfluidics



A. Schaap et al. Biophotonics 672, 661–672 (2012)

Micromechanics



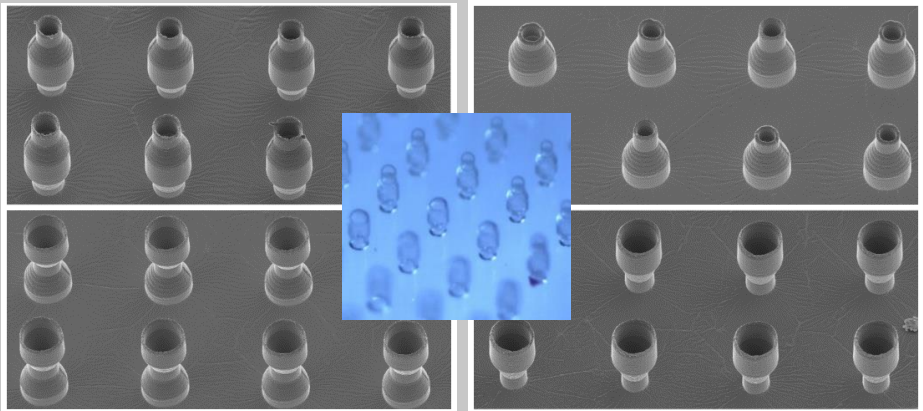
Y. Bellouard, A. Said, P. Bado, Opt. Express **13**, 6635–6644 (2005).

APPLICATIONS

Molding

3D Molds

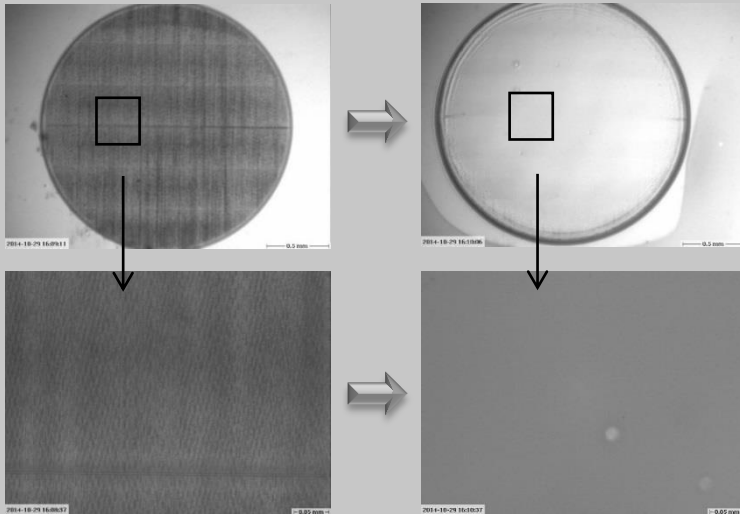
Large scale production



Allison Schaap and Yves Bellouard, *Optical Materials Express*, **3**, pp. 1428–1437 (2013)

POLISHING

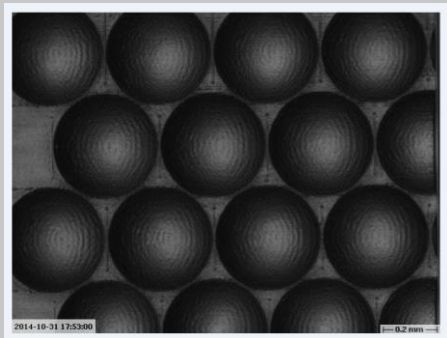
- The surface roughness of the parts after etching is $\sim 80\text{nm}$
- Polishing allows to go down to optical quality



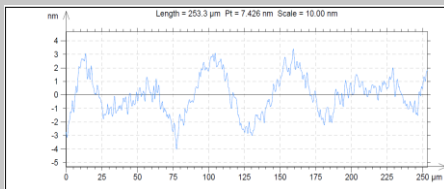
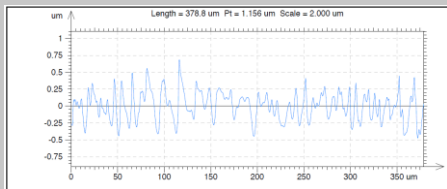
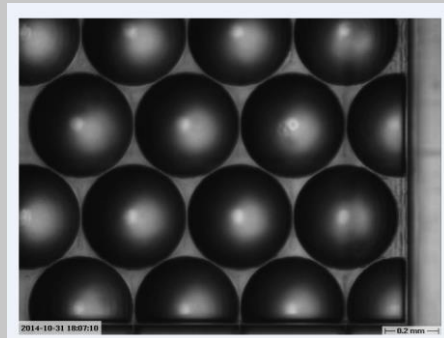
APPLICATIONS

Microlenses

- Before

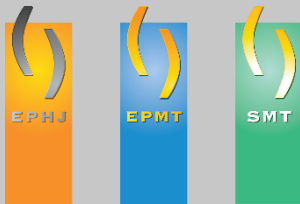


- After



CONCLUSIONS

- ✓ The technology is applicable to a wide range of «transparent» materials (fused silica, borofloat, sapphire, ruby, polymers).
- ✓ The technology is well adapted for micro rapid prototyping but also for series (mass production).



Meet with **FEMTO**print at **Stand Nr. K97**

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